



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

S. Y. LI et al.

Application No.: 09/820,695

Filed: March 30, 2001

**For: METHOD OF PLASMA ETCHING
LOW-K DIELECTRIC MATERIALS**

) **MAIL STOP AMENDMENT**
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) Group Art Unit: 1763
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) Examiner: A. W. Olsen
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) Confirmation No.: 4162
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AMENDMENT

**Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**

Sir:

In response to the Office Action mailed October 5, 2004, please amend the above-identified patent application as follows: